

Lecture 7: Process Modules III

- Announcements:
- HW#1 due tomorrow
- Module 4 online
- Videos for several of the previous lectures are now online (username and password given in last class)
- HW#2 will be online soon
- Passed out class accounts
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- Today:
- Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 3, 6
 - ↳ Example MEMS fabrication processes
 - ↳ Oxidation
 - ↳ Film Deposition
 - Evaporation
 - Sputter deposition
 - Chemical vapor deposition (CVD)
 - Plasma enhanced chemical vapor deposition (PECVD)
 - Epitaxy
 - Atomic layer deposition (ALD)
 - Electroplating
- Reading: Senturia, Chpt. 3; Jaeger, Chpt. 2, 4, 5
 - ↳ Lithography
 - ↳ Etching
 - Wet etching
 - Dry etching
 - ↳ Semiconductor Doping
 - Ion implantation
 - Diffusion
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- Last Time: going through Module 3
- Continue doing this ... then start Module 4

Contact vs. Projection Lithography (thermal expansion)



↳ a spacer: → can bow the wafer

